



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2858

Examiner: Not Yet Assigned

In Re NEW PATENT APPLICATION Of:

Applicant:

Mikio OHTAKI

Appln. No.:

09/904,663

Filed:

July 16, 2001

For:

SEMICONDUCTOR DEVICE

TEST APPARATUS

Atty Ref.:

KAN 120D1

SECOND PRELIMINARY <u>AMENDMENT</u>

October 1, 2001

Commissioner for Patents Washington, D.C. 20231

Sir:

Preliminary to examination, please amend the application as follows:

IN THE SPECIFICATION:

The following paragraph.

--FIG. 14A and FIG. 14B are plan views of a wafer to be measured that the court Deposit Account any further that the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the paragraph on page 8, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 17-19, and replace it with the page 18, lines 18, li Please delete the paragraph on page 8, lines 17-19, and replace it with the

--FIG. 14A and FIG. 14B are plan views of a wafer to be measured that may